

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			ATTY. DOCKET NO. MI22-2497		SERIAL NO. 10/776,553	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)					APPLICANT Weimin Li et al.			
					FILING DATE February 10, 2004		GROUP 1755	
U.S. PATENT DOCUMENTS								
*Examiner Initial	Document Number	Date	Name	Class	Sub-class	Filing Date If Appropriate		
DP 8/22/05	AA	5,994,217	11-1999	Ng	—			
	AB	5,991,217	11-1999	Tavrow et al.	—			
	AC	5,985,519	11-1999	Kakamu et al.	—			
	AD	5,747,388	05-1998	Koesters et al.	—			
	AE	5,639,687	06-1997	Roman et al.	—			
	AF	5,498,555	03-1998	Lin	—			
	AG	6,498,084B2	12-2002	Bergemont	—			
	AH	5,036,383	07-1991	Mori	—			
	AI	6,638,875	10-2003	Han et al.	—			
	AJ	6,720,247	04-2004	Kirkpatrick et al.	—			
	AK	6,723,631	04-2004	Noguchi et al.	—			
	AL	5,593,741	01-1997	Ikeda	—			
FOREIGN PATENT DOCUMENTS								
	Document Number	Date	Country	Class	Subclasses	Translation		
						Yes	No	
B	AM 0 471185 A2	02/92	EPO	—				
C	AN 0 484515 A3	01/92	EPO	—				
G	AO 0 771888 A1	05/97	EPO	—				
C	AP 08-213388A	08-1998	Japan	—				
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
C	AR	Wolf, "Silicon Processing for the VLSI Era, Vol. 2: Process Integration," © 1990, pp. 189-190.						
C	AS	Wolf et al., "Silicon Processing for the VLSI Era - Vol. 1 - Process Technology," Prologue, page xxiii (2 pages total).						
C	AT	Heavens, O.S., "Optical Properties of Thin Solid Films", pp. 48-49.						
EXAMINER <u>R</u>				DATE CONSIDERED <u>8/23/05</u>				
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								